



P/2850-91

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of  
Masashi UEDA et al.  
Serial No.: 10/725,905  
Filed: December 1, 2003

New York, New York  
Date: January 20, 2004  
Group Art Unit: ---  
Examiner: ---

For: METHOD AND APPARATUS FOR FORMING THIN FILMS, METHOD FOR  
MANUFACTURING SOLAR CELL, AND SOLAR CELL

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

SUBMISSION

Sir:

Submitted herewith is a copy of art together with a form listing the same for the convenience of the Examiner.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:  
Commissioner for Patents P.O. Box 1450,  
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Max Moskowitz

Name of applicant, assignee or  
Registered Representative

Signature  
January 20, 2004  
Date of Signature

Respectfully submitted,

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Enclosures

<b>APPLICANT'S ART CITATION</b> <small>(use several sheets if necessary)</small> 	Application 10/725,905		OFGS File No. P/2850-91			
	Applicant Masashi UEDA et al.					
	Filing Date December 1, 2003		Group Art Unit ---			
<b>U.S. PATENT DOCUMENTS</b>						
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub-class	
	US-5,632,821	05-1997	Doi	134	1.1	
	US-					
	US-					
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	US-					
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<b>FOREIGN PATENT DOCUMENTS</b>						
	Document Number	Date MM-YYYY	Country	Class	Translation	
					Yes	No
	2000-252496	09-2000	Japan		X	
	2003-109798	04-2003	Japan		X	
	WO 01-19144 A1	03-2001	PCT		X	
	06-283430	10-1994	Japan		X	
	2003-109798	04-2003	Japan		X	
	2918792	04-1999	Japan			X
<b>OTHER DOCUMENTS</b> (Including Author, Title, Date, Pertinent Pages, Etc.)						
		Tomoko Takagi, U.S. Patent Application Serial No. 10/276,371, filed May 17, 2001 entitled "PLASMA CVD APPARATUS AND METHOD"				
Examiner		Date Considered				
<b>EXAMINER:</b> Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.						